



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Qing Ma; Peng Cheng

Application No. 09/894,334

Filed: June 27, 2001

For: SACRIFICIAL LAYER TECHNIQUE TO MAKE

GAPS IN MEMS APPLICATIONS

Examiner: Coleman, William D.

Art Unit: 2823

## PETITION TO WITHDRAW APPLICATION FROM ISSUE UNDER 37 CFR §1.313(c)(2) IMMEDIATE CONSIDERATION REQUESTED

Mail Stop 313(c) Commissioner for Patents Post Office Box 1450 Alexandria, Virginia 22313-1450

Applicants respectfully petition for the withdrawal from issue of the above-referenced application under 37 CFR §1.313(c)(2) for consideration of a Request for Continued Examination and the enclosed Information Disclosure Statement. In connection with the petition, Applicants submit the following documents:

- (1) Check No. 0474 in the amount of \$920 which includes \$130 petition fee under 37 CFR \$1.17(h) and \$790 filing fee for Request for Continued Examination;
  - (2) a Request for Continued Examination (RCE) under 37 CFR §1.114; and
  - (3) an Information Disclosure Statement.

A Notice of Allowance in the above-referenced application was mailed on June 27, 2005. The issue fee was paid on September 23, 2005. Applicants respectfully petition that the application be withdrawn from issuance for consideration of the Request for Continued Examination (RCE) to consider the enclosed Information Disclosure Statement.

Due to the imminent possibility of the application issuing as a patent, Applicants urge the Patent Office to immediately consider and grant the petition and RCE.

In the event any additional petition fee is required for consideration of this petition, or any additional fee is required, please charge Deposit Account 02-2666.

Respectfully submitted,

BLAKELY SOKOLOFF TAYLOR & ZAFMAN LLP

Date:

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